

(19) United States

(12) Patent Application Publication (10) Pub. No.: US 2005/0184696 A1

Anastas et al.

Aug. 25, 2005 (43) **Pub. Date:**

(54) HAPTIC PROFILING SYSTEM AND **METHOD**

(52) **U.S. Cl.** **318/567**; 345/156; 345/157; 345/161; 345/163; 345/419; 318/568.1

ABSTRACT

(76) Inventors: George V. Anastas, San Carlos, CA

(US); Michael D. Levin, Los Altos, CA (US); Danny Grant, Montreal (CA); Juan Manuel Cruz-Hernandez, Montreal (CA); Pedro Gregorio, Montreal (CA); Christophe Ramstein,

San Francisco, CA (US)

(57)

Correspondence Address: David B. Ritchie Thelen Reid & Priest LLP P.O. Box 640640 San Jose, CA 95164-0640 (US)

(21) Appl. No.: 11/014,218

Dec. 17, 2004 (22) Filed:

Related U.S. Application Data

(60) Provisional application No. 60/531,416, filed on Dec. 19, 2003. Provisional application No. 60/551,054, filed on Mar. 9, 2004.

Publication Classification

(51) **Int. Cl.**⁷ **G05B 19/10**; G09G 5/00; G09G 5/08; G06T 15/00; G05B 19/18 An apparatus includes a characterization module configured to receive data associated with operational characteristics of a mechanical device, the operational characteristics being associated with a perceptual experience of the mechanical device. A conversion module is coupled to the characterization module. The conversion module is configured to automatically produce, substantially without user intervention, a parametric data set associated with the mechanical device based on the data. In another embodiment, a method includes receiving data associated with operational characteristics of a mechanical device. The operational characteristics are associated with a perceptual experience of the mechanical device. A parametric data set associated with the mechanical device is produced automatically, without user intervention. The parametric data set is associated with the mechanical device based on the data.

